

High resolution TEM of organic molecules?

Cécile Hébert, EPFL

Layout



- Introduction: history and description of the TEM
- Contrast mechanisms
 - Mass-Thickness
 - Diffraction
 - Phase
 - Mass-Thickness in STEM
- Aberrations and their corrections
- Examples

30/07/15

Summer School of the MP-EPFL Center, Schloss Ringberg 2015

Layout

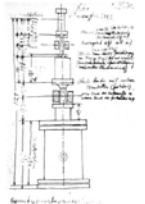


- Introduction: history and description of the TEM
- Contrast mechanisms
 - Mass-Thickness
 - Diffraction
 - Phase
 - Mass-Thickness in STEM
- Aberrations and their corrections
- Examples


30/07/15

Summer School of the MP-EPFL Center, Schloss Ringberg 2015

History of TEM



Sketch of first TEM by Ruska, 1931



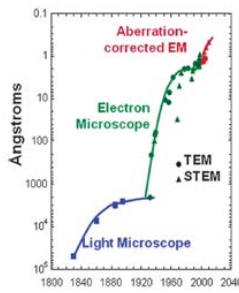
E. Ruska

- 1931: Knoll & Ruska build the first prototype
- 1933: The TEM surpasses the light microscope in resolution
- 1939: first commercial instrument
- 1986 E. Ruska is awarded the Nobel prize

From *Jacob Lechman, Physics 1981-1990*, Editor-in-Charge Tone Frångmyr, Editor Gösta Ekqvist, World Scientific Publishing Co., Singapore, 1993

30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

History of TEM



- Abbe diffraction limit for the light microscope

$$d = \frac{\lambda}{2n \sin \theta}$$
- Equivalent for the electron microscope


$$d = \frac{1.2\lambda}{\sin \theta}$$

$\lambda = 2.5 \cdot 10^{-12} \text{ m @ 200 kV;}$
 $\theta \approx 10 - 20 \text{ mrad}$
 $\Rightarrow d \text{ 1.5 to 3 \AA}$

S. J. Pennycook & et al., in: *The Oxford Handbook of Nanoscience and Nanotechnology*, ed. A. V. Marikar and Y. Y. Fu, Oxford University Press, Oxford, United Kingdom, 2010, p. 205.

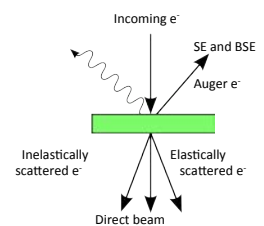
30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

The constituent of the TEM




A typical TEM: Jeol 200cx

Probe = electrons
 100-300 kV
 Velocity: 0.55-0.77 c




Incomig e⁻, SE and BSE, Auger e⁻, Inelastically scattered e⁻, Direct beam, Elastically scattered e⁻

30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015


Layout 

- Introduction: history and description of the TEM
- Contrast mechanisms
 - Mass-Thickness
 - Diffraction
 - Phase
 - Mass-Thickness in STEM
- Aberrations and their corrections
- Examples

30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

Contrast formation in the TEM 

- Mass-thickness contrast
- Diffraction
- Phase Contrast (High resolution)
- Scanning TEM: Mass-thickness contrast (Z-contrast)
- Chemical contrast (additional devices)

Contrast formation in the TEM 

- Mass-thickness contrast
 - All specimens with variation of thickness and/or different Z
- Diffraction
 - All crystalline specimen
- Phase Contrast (High resolution)
 - Thin specimen; crystalline specimen in high resolution
- Scanning TEM: Mass-thickness contrast (Z-contrast)
 - All specimens with variation of thickness and/or different Z
 - Caution diffraction contrast may appear too
- Chemical contrast (additional devices)
 - All specimen

The objective lens

Specimen (object)

Objective lens

Back focal plane : diffraction pattern
Objective Aperture

Image (first intermediate)

TEM mass-thickness contrast

Lower mass thickness

Incident beam

Higher mass thickness

Objective lens

Objective aperture

Image plane

Intensity profile

- Areas of higher mass thickness scatter electrons more than others
- Electrons are captured by the aperture and lost from the beam path
- Areas of higher mass thickness will therefore appear dark in the image
- This is known as
 - mass thickness contrast,
 - scattering contrast,
 - aperture contrast or
 - amplitude contrast!

No aperture

Aperture

Diffraction contrast

Examples:

Nanocrystal

Twinning

Bright-field/dark-field imaging

Nickel based superalloys
Contrast ψ/ψ'

Phase contrast

Phase contrast

Scattered Ψ'


Incident Ψ

Detector: $\Psi' * \Psi' = \Psi^2 [1 + f^2(r)]$

$\Psi' = \Psi \exp [if(r)]$
 $\Psi' = \Psi [1 + if(r) - \frac{1}{2}f^2(r) + \dots]$
 $\Psi' \approx \Psi [1 + if(r)], f(r) \ll 1$


Virtually no contrast in the image plane

Phase contrast



- EM is an imperfect microscope:
 - Low coherence source
 - Chromatic aberration
 - Spherical aberration
 - Other problems...
- These 'features' result in the loss of resolution, but help to generate contrast
- Defocus can also generate contrast

Contrast transfer function




- The lens applies a phase shift χ , dependent on scattering angle θ

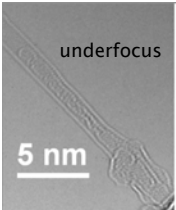
$$\chi(\theta) = 2\pi/\lambda (\frac{1}{2} \Delta f \theta^2 + \frac{1}{4} C_s \theta^4)$$
 where C_s is the spherical aberration and Δf is the defocus, λ is the electron wavelength.
- The angle θ is related to the spatial frequency ν

$$\theta \approx \lambda \nu$$

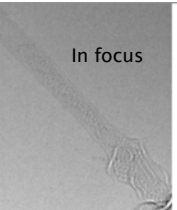
$$\chi(\nu) = \pi \lambda (\Delta f \nu^2 + \frac{1}{2} C_s \lambda^2 \nu^4)$$
- The phase shift $\chi(\nu)$ leads to contrast enhancements at specific Δf .

Resolution / Contrast tradeoff

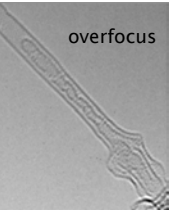




underfocus



In focus



overfocus

Carbon nanotubes filled with sextiophene

Phase contrast for crystalline specimen

Sounds simple:

Electron beam

Crystal structure properly oriented

Objective lens

Projected image

Si [110] orientation

Phase contrast for crystalline specimen

Unfortunately things are much more complicated

Electron beam

Crystal structure properly oriented. Affects phase and amplitude of the beam in a complicated way

Direct and Diffracted beams (Phase shift!)

Objective lens (with aberrations affects phase shifts)

Mixing of information from the sample and microscope via INTERFERENCES!

Projected **amplitude** after interference!

Phase contrast for crystalline specimen

$\psi_o(\vec{r})$ Wave function after the object depends on object nature and thickness

Objective lens not perfect $T(\vec{r})$ Point spread function

OL BF plane

$\psi_i(\vec{k}) = \psi_o(\vec{k}) T(\vec{k})$

$T(\vec{k})$ Transfer function

$\psi_i(\vec{r}) = \int_{-\infty}^{+\infty} \psi_o(\vec{u}) T(\vec{r} - \vec{u}) d\vec{u}$

Phase contrast for crystalline specimen

Thickness-defocus map in Fe₃Al intermetallics

Next nearest neighbour antiphase boundary in the Fe₃Al based intermetallics. The inset shows simulation of the atomic configuration of the defect.

Miroslav Karlik
Materials Structure, 8 (2001) 3

Phase contrast for crystalline specimen

300 kV, Cs 0.7mm, defocus -1009 nm, astigm 2 nm, -28°

300 kV, Cs 0.7mm, defocus -229 nm, astigm 10 nm, -82°

300 kV, Cs 0.7mm, defocus -40 nm, astigm 1 nm, 65°

Scanning TEM (STEM)

Z-contrast examples:

Focused e⁻ probe scanned on sample; disc and annular detectors in back focal (diffraction) plane


Backscattered convergent beam
Scan beam
Specimen
XRF detector
EDS spectrometer
BF detector

Pt catalyst on Al₂O₃ Si-Ge/Si multilayer

High-angle annular dark-field => compositional contrast: intensity ∝ tZ² (thickness t, atomic number Z)

Cs-corrected - graphene with dopant atoms (Krivanek et al., Nion)


Layout



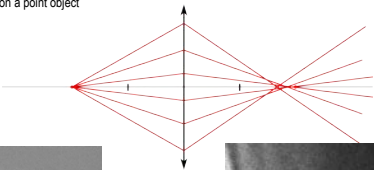
- Introduction: history and description of the TEM
- Contrast mechanisms
 - Mass-Thickness
 - Diffraction
 - Phase
 - Mass-Thickness in STEM
- Aberrations and their corrections
- Examples

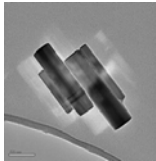
30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

Lenses aberrations: spherical aberration

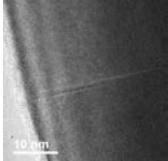


- Effect on a point object






Creates ghost images

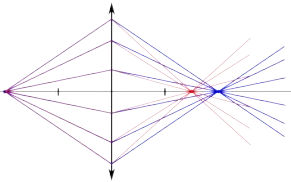


Blurs interfaces

30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

Lenses aberrations: chromatic aberration






- Results in a blurring of the image
- Small energy spread of the probe (monochromator) and thin specimen reduces the impact
- Correctors are developed in few labs
- To be considered at very low tension and for analytical TEM (energy loss spectrometry)

30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

Lenses aberrations: historical note



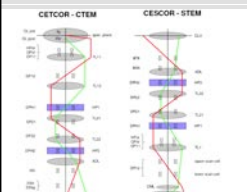

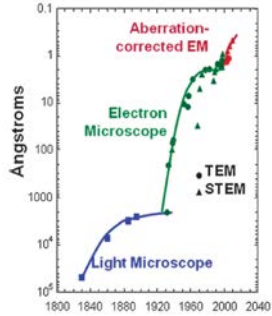
- O. Scherzer
- 1936: Cs and Cc are always positive for lenses with cylindrical symmetry
- 1947: proposition for a solution (O. Scherzer, Optik, 1947)
- 1997: first successful correction!

Über einige Fehler von Elektronenlinsen.
 Von O. Scherzer in Darmstadt.
 Mit 3 Abbildungen. (Eingegangen am 4. Juni 1936.)
 Unmöglichkeit des Achromaten. Die Bildfehler dritter Ordnung. Unvermeidbarkeit der sphärischen Aberration.

Zusammenfassung. Chromatische und sphärische Aberration sind unvermeidbare Fehler der räumlichsfreien Elektronenlinse. Verrückelung (Zerlehnung wie Zerdrückung) und (alle Arten von) Koma lassen sich prinzipiell beseitigen. Durch die Unvermeidbarkeit der sphärischen Aberration ist eine praktische, nicht aber eine prinzipielle Schranke für das Auflösungsvermögen der Elektronenmikroskope gegeben.

30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015




Cs correction

The graph shows the evolution of resolution in Angstroms over time. The y-axis is logarithmic, ranging from 10⁰ to 10¹ Angstroms. The x-axis shows years from 1800 to 2040. Key points include: Light Microscope (around 1800, ~20000 Å), Electron Microscope (around 1930, ~100 Å), TEM (around 1950, ~10 Å), and Aberration-corrected EM (starting around 1990, reaching ~0.5 Å by 2040). STEM is also marked around 1950.


Cc correction: Work in progress

- Cc correction


Work in the CEOS lab: SALVE II TEM, built by ZEISS, C_c/C_s-corrector by...

The advantages



- Improved resolution
 - At lower voltage! (beam sensitive materials)
 - For large pole piece gap (in-situ experiments possible)
- Higher precision (better contrast)
 - Lower dose possible
 - Higher frame rate (video)
- Less delocalisation


Layout



- Introduction: history and description of the TEM
- Contrast mechanisms
 - Mass-Thickness
 - Diffraction
 - Phase
 - Mass-Thickness in STEM
- Aberrations and their corrections
- Examples

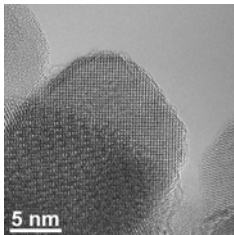
30/07/15 Summer School of the MP-EPFL Center, Schloss Ringberg 2015

Imaging of functionalized nanoparticles



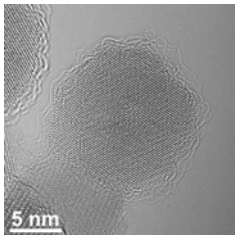
Monochromated, Cs-corrected TEM at 80 kV

Few atom functional group



5 nm

Larger functional group



5 nm

Duncan Alexander, CIME with LTP

